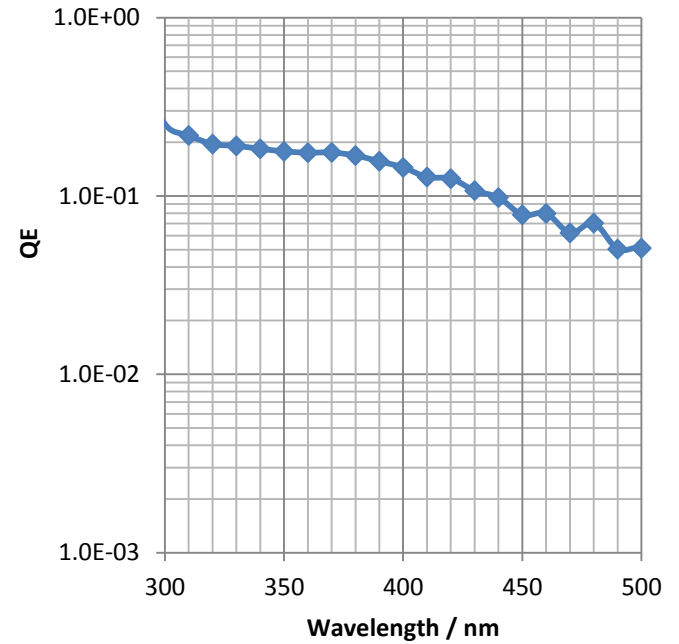
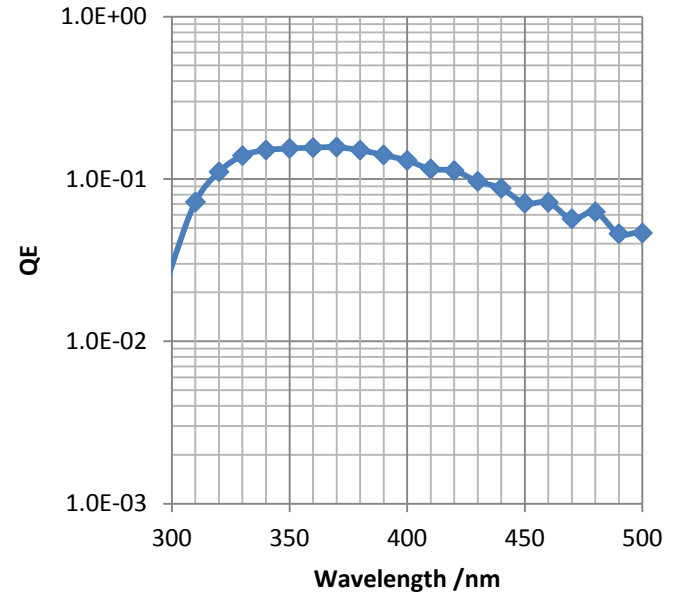
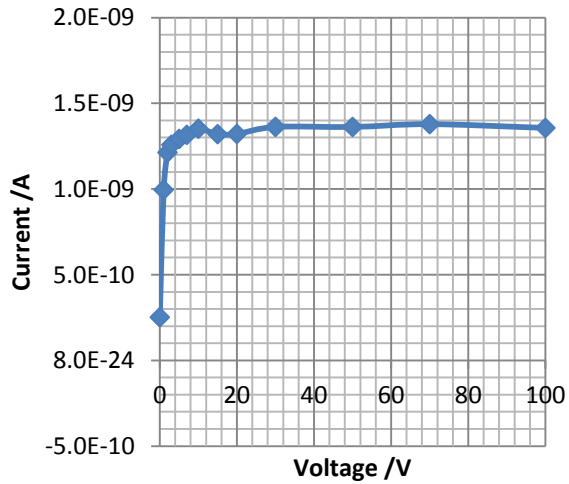


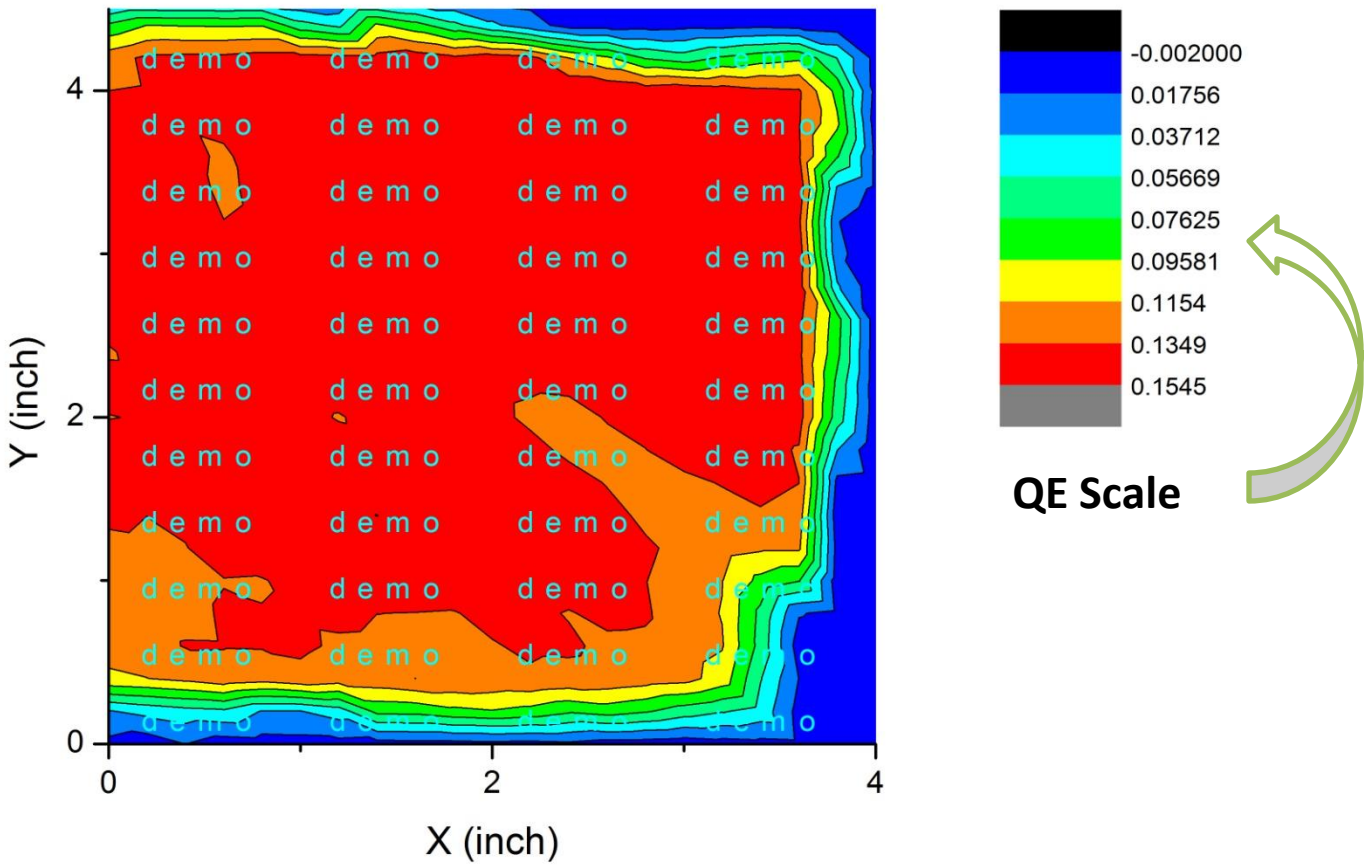
# Chalice cathode deposition #4

Chalice cathode #4 used 4 K and 4 Cs dispensers. K is not enough, 6 K is good for chalice deposition.



# Chalice cathode deposition #4 Map

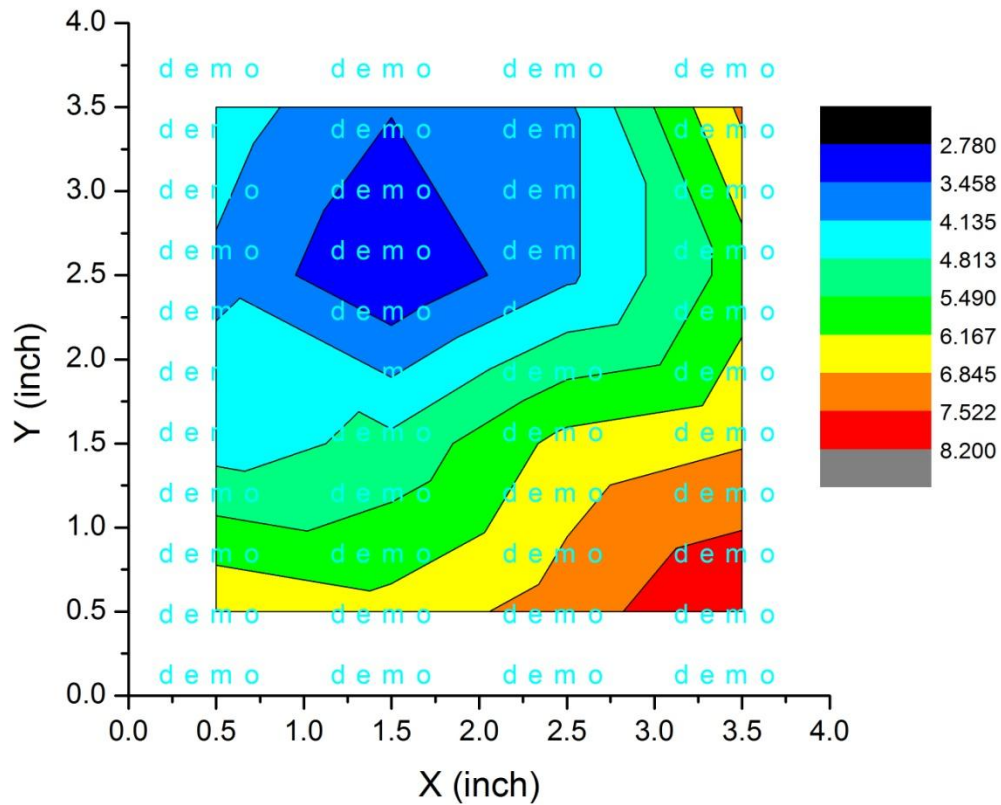
The QE mapping is obtained at 350 nm wavelength, scan step size: 0.2 inch



The blue areas are the Al coating area. The “demo” logo is because I am using the origin evaluation software, which I do not have the license. Sorry for that.

# Chalice cathode deposition #4 Map

## Sb Reflectivity mapping during deposition



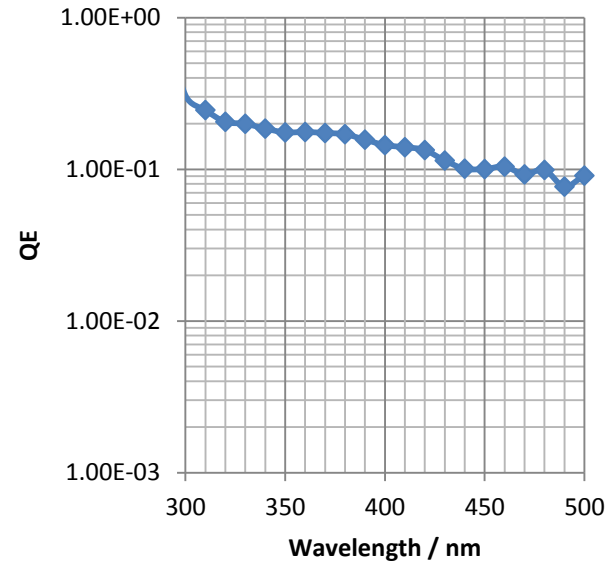
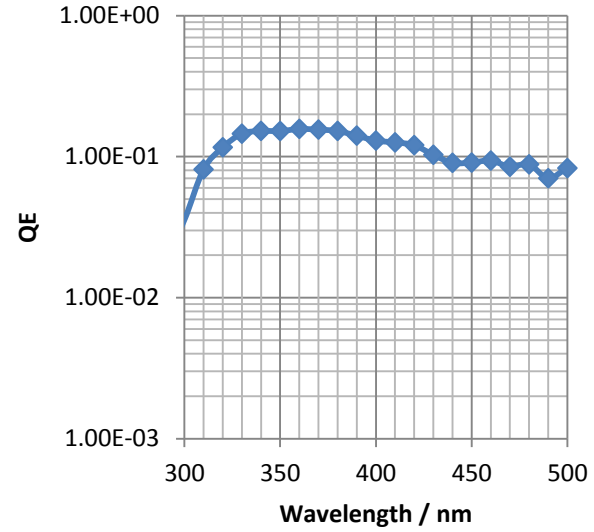
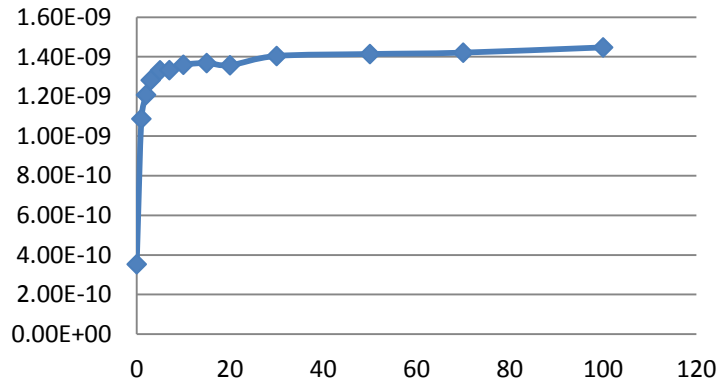
Sb film reflected beam intensity  
Unit: 1E-8 A

4.5	3.5	4.0	7.0
4.0	2.8	4.0	5.8
4.5	5.0	6.4	6.8
6.8	6.4	7.2	8.2

# Chalice cathode deposition #4

## - Pumping over 3 days

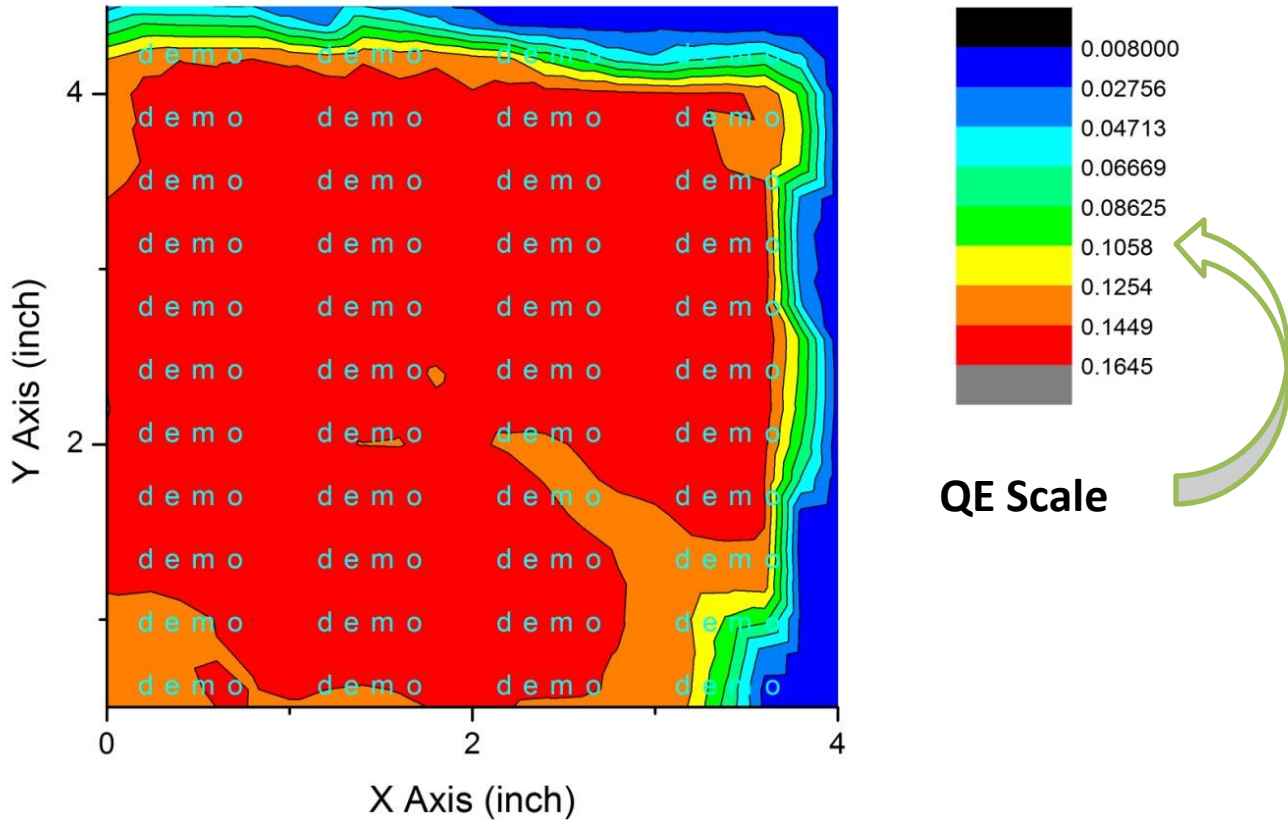
### I-V



# Chalice cathode deposition #4 Map

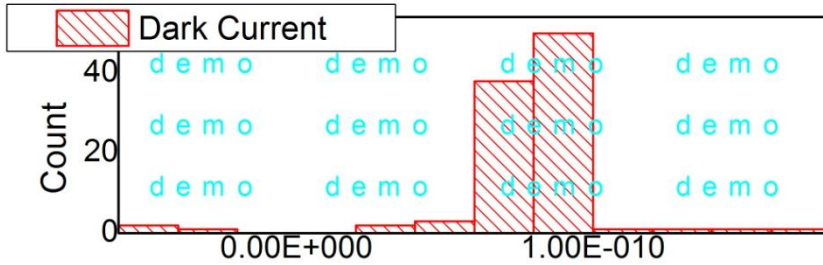
## - Pumping over 3 days

The QE mapping is obtained at 350 nm wavelength, scan step size: 0.2 inch



# Chalice cathode deposition #4

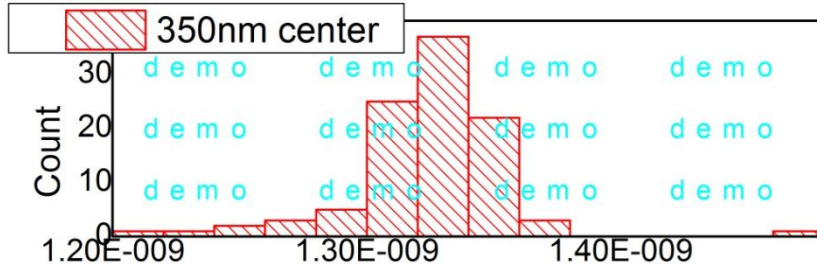
## - Uncertainty



**Dark current – center area**

Mean: 7.72E-11 A

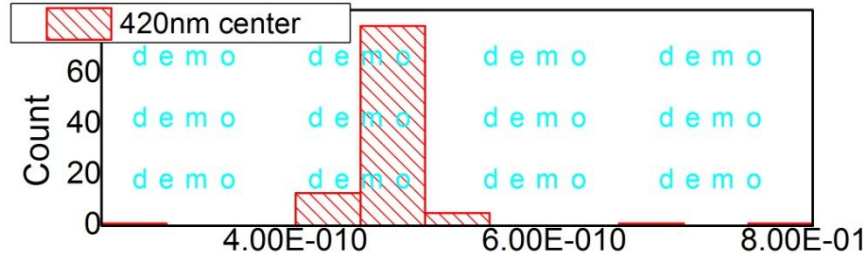
Standard Deviation: 2.69E-11 A



**Photo current at 350 nm – center area**

Mean: 1.32E-9A

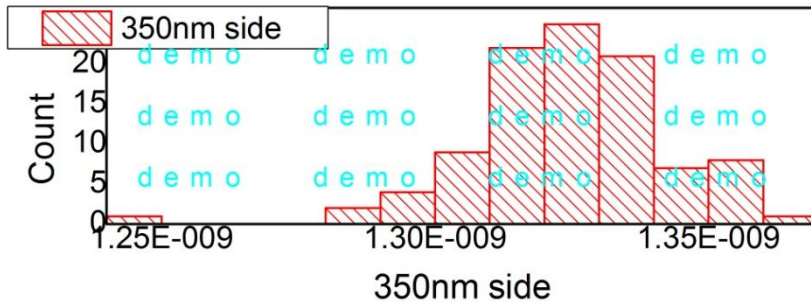
Standard Deviation: 2.93E-11A



**Photo current at 420 nm – side area**

Mean: 4.70E-10 A

Standard Deviation: 4.45E-11 A



**Photo current at 350 nm – side area**

Mean: 1.32E-9 A

Standard Deviation: 1.78E-11 A